

Form PTO-1449 INFORMATION DISCLOSURE CITATION IN AN APPLICATION (Use several sheets if necessary)	ATTY DOCKET NO. 2691-000013/US	APPLICATION NO. NEW APPLICATION
	APPLICANT(S) Kohshi TAGUCHI et al.	CONF. NO. Unknown
	FILING DATE January 7, 2005	GROUP Unknown


U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE

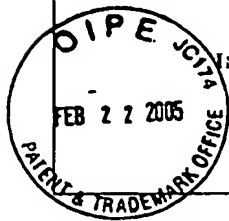
FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION	
						YES	NO
HEA	JP 5-263255 A	10/12/1993	JAPAN				
HEA	EP 300447 A2	10/05/2001	EUROPE				
HEA	JP 9-41147 A	02/10/1997	JAPAN				

OTHER DOCUMENTS (Include Name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.) date, page(s), volume-issue number(s), publisher, city and/or country where published.

EXAMINER 	DATE CONSIDERED 9/27/05
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



FORM HDP-1449 (Based on Form PTO-1449)

PATENT AND TRADEMARK OFFICE
INFORMATION DISCLOSURE CITATION
(Use several sheets if necessary)

Sheet 1 of 1

ATTORNEY DOCKET NO.

2691-000013/US

SERIAL NO.

10/520,815

APPLICANTS

Kohshi TAGUCHI et al.

FILING DATE

January 7, 2005

GROUP

Unknown

U.S. PATENT DOCUMENTS

Ref. Desig.	Examiner's Initials	Document Number	Date	Name	Class/ Subclass	(If appropriate) Filing Date
	HEA	US 5,508,067	04/16/1996	Tatsuya SATO et al.		
	HEA	US 5,591,494	01/07/1997	Tatsuya SATO et al.		

FOREIGN PATENT DOCUMENTS

Ref. Desig.	Examiner's Initials	Document Number	Date	Country	Class/ Subclass	Translation Yes	No
	HEA	JP 2001-23904	01/26/2001	JAPAN		ABST.	
	HEA	JP 7-106256	04/21/1995	JAPAN		ABST.	
	HEA	JP 5-263255	10/12/1993	JAPAN		ABST.	
	HEA	EP 0 300 447 A2	01/25/1989	EUROPE		X	
	HEA	JP 9-41147	02/10/1997	JAPAN		ABST.	

OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages, etc.)

Ref. Desig.	Examiner's Initials	
		Y. HATANAKA et al., "Remote plasma depositions of SiC _x N _y film using hexamethyldisilazane", Proc. of 6 th Int. Conf. Silicon Carbide and Related Materials Kyoto, IOP Conf., Ser. No. 142, Pages 1055-1058, 1995

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Examiner:

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